

(Use several sheets if necessary)

Application Number:

$$10 \mid 723,236$$

Chan Hsien Lin et al.

11/26/03

Growth Art Unit

[illegible]

U J. Zhang et al., "Automated Process Control of Within-Wafer and Wafer-to-Wafer Uniformity in Oxide CMP," Online March 2002, CMP MIC [retrieved on Jan. 27, 2003] retrieve from URL: [REDACTED]

Wilson

9/15/05 3/6/06

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STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet 1 of 1**Complete if Known**

Application Number	10/723236
Filing Date	November 26, 2003
First Named Inventor	Chun-Hsien Lin et al.
Art Unit	2812
Examiner Name	Lee D. Wilson
Attorney Docket Number	2002-0992/24061.495

U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
LW	AA	US- 5655951	08-12-1997	Meikle et al.	
	AB	US- 5719495	02-17-1998	Moslehi	
	AC	US- 6148239	11-14-2000	Funk et al.	
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	AE	US- 6372632	04-16-2002	Yu et al.	
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FOREIGN PATENT DOCUMENTS

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